






**Ceramic capacitance pressure sensor**

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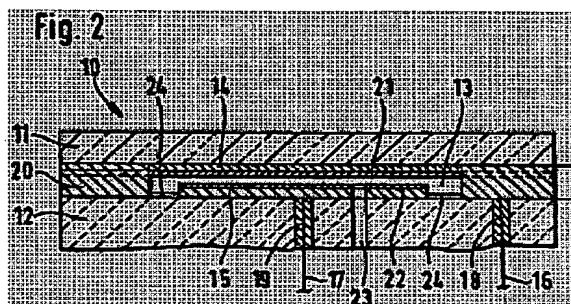
**Cited documents:**

 US5050034  
 JP8189870

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**Abstract of EP1061351**

The relative pressure sensor includes a diaphragm (11) with a first electrode (14) applied to its surface. A hole (23) is provided in a base body (12) for guiding reference air from a first surface to an opposing second surface. The first surface is polished and a second electrode (15) is applied to it. The base body and diaphragm are soldered or brazed together at the edge, with spacers (20) forming a chamber (13). The chamber is covered from the inside with a thin layer (24) of hydrophobic material which is brought in through the hole (23) after the soldering or brazing.



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